Chemraz XPE

Perfluoroelastomer

Greene, Tweed & Co.

Message:

Protection against oxygen-infused plasma is key in many etch chamber environments. These harsh environments often breakdown non-resistant materials, causing harmful particulation and, ultimately, defective chips.
Greene, Tweed's Chemraz® XPE is highly resistant to O2 plasma and can be used in a wide range of applications, such as slit valve doors, reaction chamber lid seals, and gate valve seals. This advanced elastomeric material offers the semiconductor and solar industry an alternative to legacy products that quickly erode in the oxygen environment. With excellent resistance to both 02 and CF4 plasmas, this material affords an increased chip yield and maximized production. In addition, XPE seals provide customers with an increased MTBR (mean time between repair) to reduce downtime and maintenance costs.

General Information			
Uses	Seals Valves/Valve Parts		
Appearance	Grey		
Forms	Pellets		
Physical	**Nominal Value**	**Unit**	**Test Method**
Specific Gravity	2.12	g/cm³	ASTM D792
Hardness	**Nominal Value**	**Unit**	**Test Method**
Rockwell Hardness (M-Scale)	76		ASTM D1414
Durometer Hardness (Shore A)	73		ASTM D2240
Elastomers	**Nominal Value**	**Unit**	**Test Method**
Tensile Stress (100% Strain)	3.63	MPa	ASTM D1414
Tensile Strength (Break)	13.3	MPa	ASTM D1414
Tensile Elongation (Break)	220	%	ASTM D1414
Compression Set [1]			
204°C, 70 hr	15	%	
240°C, 70 hr	22	%	
Thermal	**Nominal Value**	**Unit**	
Service Temperature	280	°C	
NOTE			
1.	25% Deflection		

Recommended distributors for this material

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